ABSTRACT OF THE DISCLOSURE (FIG. 3)

"FILM QUALITY INSPECTING METHOD
AND FILM QUALITY INSPECTING APPARATUS"

A film quality inspecting method comprising applying a measuring beam having a specific wavelength to an annealed silicon film formed on a substrate in a direction inclined with respect to the silicon film, measuring a reflection intensity or reflectivity of a reflection beam reflected by the silicon film as a result of the application, and inspecting a film quality of the silicon film based on a measurement value obtained by the measurement.

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